

AMENDMENT TO THE CLAIMS:

1 - 14 (Cancelled)

15. (Original) A method of reworking interconnection layers above logical and functional layers of an integrated circuit structure, wherein said interconnection layers comprise an upper insulator layer above a lower insulator layer and electrical wiring, wherein said lower insulator layer has a lower dielectric constant than that of said upper insulator layer, said method comprising:

removing a first upper insulator of a first interconnection layer of said interconnection layers; and

removing a first electrical wiring and a first lower insulator of said first interconnection layer in a selective removal process that does not affect a second upper insulator of a second interconnect layer positioned immediately below said first interconnect layer.

16. (Original) The method in claim 15, wherein said second upper insulator protects a second lower insulator of said second interconnect layer during said process of removing said first electrical wiring and said first lower insulator.

17. (Original) The method in claim 15, wherein said removing processes completely remove said first interconnection layer and leave said second interconnection layer in tact, wherein said

method further comprises forming a replacement interconnect layer in place of said first interconnect layer.

18. (Original) The method in claim 15, wherein said process of removing said first upper insulator also removes a portion of said first lower insulator and exposes portions of said electrical wiring,

wherein said method further comprises, after said process of removing said first upper

depositing an etch stop layer on partially removed portions of said first lower insulator and on exposed portions of said electrical wiring.

19. (Original) The method in claim 18, further comprising after said process of depositing said etch stop layer:

removing said metal wiring, thereby leaving said partially removed portions of said first lower insulator and portions of said etch stop layer; and

removing said etch stop layer.

20. (Original) The method in claim 19, wherein said etch stop layer protects said first lower insulator during said process of removing said metal wiring.